

Docket No.: 071971-0432

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 53080
	:	
Satoshi SHIBATA	:	Confirmation Number: 2300
	:	
Application No.: 10/557,746	:	Group Art Unit: 2813
	:	
Filed: November 21, 2005	:	Examiner: Latanya N. CRAWFORD
	:	
For: MANUFACTURING METHOD OF A SEMICONDUCTOR DEVICE	:	

REQUEST FOR COMPLETE
ACKNOWLEDGEMENT OF THE CITED ART

Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

We are in receipt of the Notice of Allowance dated February 5, 2010.

In reviewing the file, it is noted that we have not received a **complete** acknowledgement of the Information Disclosure Statement and cited art filed November 21, 2005. Specifically, under the section "Other Art", the reference "Borland "Low Temperature Activation of Ion Implanted Dopants: A Review", Japan Society of Applied Physics, 2002, pp. 85-88", as listed on the 1449 Form and has not been acknowledged. Enclosed are copies of the Information Disclosure Statement and PTO-1449 Form. Also enclosed please find a copy of the partially initialed PTO-1449 Form received with the Office Action dated June 12, 2007.


Applicant hereby respectfully requests that:

- (1) the **completely** acknowledged PTO-1449 be furnished to Applicant; and
- (2) the record be clarified to confirm that the cited art has been considered and made

of record.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP


Michael E. Fogarty
Registration No. 36,139

**Please recognize our Customer No. 53080
as our correspondence address.**

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Phone: 202.756.8000 MEF:alb
Facsimile: 202.756.8087
Date: March 15, 2010

Docket No.: 071971-0432

PATENT**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:	Customer Number: 20277
	:	
Satoshi SHIBATA	:	Confirmation Number: Not yet
assigned	:	
	:	
Application No.: Not yet assigned	:	Group Art Unit: Not yet assigned
	:	
Filed: November 21, 2005	:	Examiner: Not yet assigned
	:	
For: MANUFACTURING METHOD OF A SEMICONDUCTOR DEVICE	:	

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents and Trademarks
Washington, D. C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed with the application and no certification or fee is required.

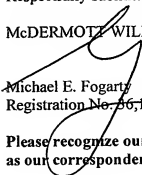
A copy of the foreign search report is attached for the Examiner's information. Please note this is a PCT application in the entry of the National Phase in the U.S. and copies of the references cited were transmitted by WIPO and are believed to be in the file of the above identified application and readily available to the Examiner. Therefore it is believed that Applicants have met all requirements regarding duty of disclosure under 37

CFR 1.56. Acknowledgement and consideration of these documents are respectfully requested.

A copy of the foreign search report is attached for the Examiner's information. Please note this is a PCT application in the entry of the National Phase in the U.S. Since the Search Report was from the U.S. JPO or EPO search authorities, copies of these references should have been supplied to the USPTO under the trilateral agreement and are believed to be in the file of the above identified application and readily available to the Examiner.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP


Michael E. Fogarty
Registration No. 36,139

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Date: November 21, 2005

[illegible]

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

ATTY. DOCKET NO.
071971-0432

SERIAL NO.
Not yet assigned
10/557746

(PTO-1449)

APPLICANT
Satoshi SHIBATA

FILING DATE
November 21, 2005

GROUP
Not yet assigned **2809**

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
ILC/		US 6,074,937	6-13-2000	Pramanick, et al.	
ILC/		US 5,602,045	2-11-1997	Kimura	
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FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes-Number + Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation Yes No
ILC/		JP 04-058524	2-25-1992	Fujitsu Ltd.		
ILC/		JP 06-089869	3-29-1994	Ok Electric Industry Co., Ltd.		
ILC/		JP 05-190850	7-30-1993	Sony Corp		
ILC/		JP 08-203842	8-9-1996	Sony Corp		

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
		BORLAND "Low Temperature Activation of Ion Implanted Dopants: A Review", Japan Society of Applied Physics, 2002, pp. 85-86

EXAMINER

/Latanya Crawford/

DATE CONSIDERED

06/04/2007

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.